



Designation: E2444-05^{ε1} Designation: E2444-11

Terminology Relating to Measurements Taken on Thin, Reflecting Films¹

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~~^{ε1}Note—Editorial changes were made throughout in January 2006.~~

1. Scope

1.1 This standard consists of terms and definitions pertaining to measurements taken on thin, reflecting films, such as found in microelectromechanical systems (MEMS) materials. In particular, the terms are related to the standards in Section 2, which were generated by Committee E08 on Fatigue and Fracture. Terminology E1823 Relating to Fatigue and Fracture Testing is applicable to this standard.

1.2 The terms are listed in alphabetical order.

2. Referenced Documents

2.1 *ASTM Standards:*²

E1823 Terminology Relating to Fatigue and Fracture Testing

E2244 Test Method for In-Plane Length Measurements of Thin, Reflecting Films Using an Optical Interferometer

E2245 Test Method for Residual Strain Measurements of Thin, Reflecting Films Using an Optical Interferometer

E2246 Test Method for Strain Gradient Measurements of Thin, Reflecting Films Using an Optical Interferometer

3. Terminology

3.1 *Terms and Their Definitions:*

2-D data trace—a two-dimensional group of points that is extracted from a topographical 3-D data set and that is parallel to the ~~*xz-* or *yz-*plane of the interferometer.~~ *plane of the interferometric microscope.* E2244, E2245

3-D data set—a three-dimensional group of points with a topographical *z*-value for each (*x*, *y*) pixel location within the ~~interferometric microscope's~~ *interferometric microscope's* field of view. E2244, E2245, E2246

anchor—in a surface-micromachining process, the portion of the test structure where a structural layer is intentionally attached to its underlying layer. E2244, E2245, E2246

anchor lip—in a surface-micromachining process, the freestanding extension of the structural layer of interest around the edges of the anchor to its underlying layer. E2244, E2245, E2246

~~DISCUSSION—~~In some processes, the width of the anchor lip may be zero. E2244, E2245, E2246

bulk micromachining—a MEMS fabrication process where the substrate is removed at specified locations. E2244, E2245, E2246

cantilever—a test structure that consists of a freestanding beam that is fixed at one end. E2246— E2244, E2245, E2246

fixed-fixed beam—a test structure that consists of a freestanding beam that is fixed at both ends. E2245— E2244, E2245

in-plane length (or deflection) measurement, *L* (or *D*) [L]—the experimental determination of the straight-line distance between two transitional edges in a MEMS device.

~~DISCUSSION—~~This length (or deflection) measurement is made parallel to the underlying layer (or the *xy*-plane of the interferometer).—E2244
-plane of the interferometric microscope). E2244, E2245, E2246

interferometer—a non-contact optical instrument used to obtain topographical 3-D data sets.

¹ This test method is under the jurisdiction of ASTM Committee E08 on Fatigue and Fracture and is the direct responsibility of Subcommittee E08.02 on Standards and Terminology.

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² For referenced ASTM standards, visit the ASTM website, www.astm.org, or contact ASTM Customer Service at service@astm.org. For *Annual Book of ASTM Standards* volume information, refer to the standard's Document Summary page on the ASTM website.